



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Hou, Chien-Chou; et al.) Examiner: Deo, Duy Vu N'Guyen
Serial No.: 10/600,377)) Art Unit: 1765
Filed: June 20, 2003)) Our Ref: B-5130 621033-6
For: "METHOD OF ETCHING UNIFORM) Date: March 2, 2007
SILICON LAYER")) Re: *Amendment and Response*
))

AMENDMENT AND RESPONSE

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is in reply to the non-final Office Action mailed on December 4, 2006, an initial response to which is due no later than

March 5, 2007.

(Monday)

Please amend the above-identified application as described below and consider the following remarks. All amendments and remarks herein are made without prejudice.

Amendments to the Claims are reflected in the listing of claims that begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.